

PATENT ABSTRACTS OF JAPAN

(11)Publication number : **07-325036**
 (43)Date of publication of application : **12.12.1995**

(51)Int.CI. G01N 21/84
 G01B 11/30
 G01N 21/88
 H01L 21/66
 // G02B 13/22

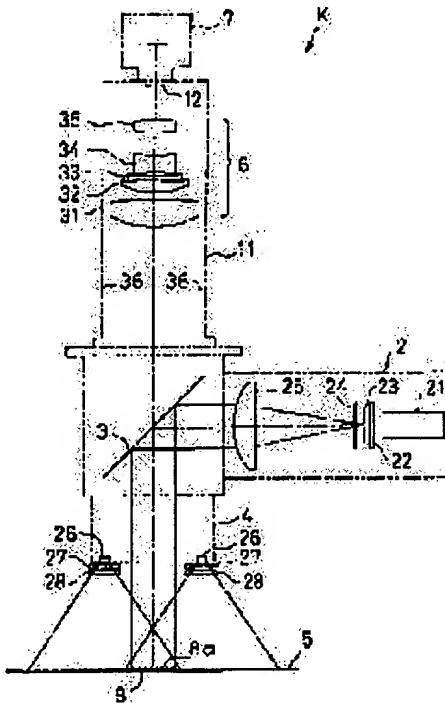
(21)Application number : **06-141118** (71)Applicant : **NEW KURIEISHIYON:KK**
 (22)Date of filing : **31.05.1994** (72)Inventor : **HAGA KAZUMI**

(54) OPTICAL SYSTEM FOR INSPECTION, AND INSPECTION APPARATUS

(57)Abstract:

PURPOSE: To extend the depth of a field in which a picture can be taken and provide an inspection apparatus in which an observation part can be included easily within a range of focuses.

CONSTITUTION: Regarding an optical system K for inspection in which parallel light rays are radiated to a specimen 8 by a radiation optical system K, the transmitted light rays or the reflected light rays are converged by an observation optical system 6, and observation of the specimen 8 is done by the observation part 7 in the rear side of the optical system 6, the optical system K for inspection is characteristically provided with the observation optical system K having a telecentric optical part 6 and an iris diaphragm 12 set in a rear image spatial focusing plane of the telecentric optical part 6 or near the plane.



LEGAL STATUS

[Date of request for examination] **20.04.2001**

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]